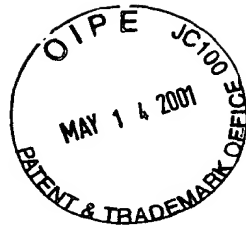


#5 IDS  
M. Brunson  
5/18/01



XA-9387

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hitoshi TAKEUCHI

Group Art Unit: 2877

Appln. No.: 09/714,183

Filed: November 17, 2000

For: ABERRATION MEASURING APPARATUS, ABERRATION MEASURING METHOD, PROJECTION EXPOSURE APPARATUS HAVING THE SAME MEASURING APPARATUS, DEVICE MANUFACTURING METHOD USING THE SAME MEASURING METHOD, AND EXPOSURE METHOD

\* \* \*

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

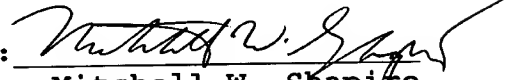
RECEIVED  
MAY 15 2001  
TC 2800 MAIL ROOM

Pursuant to 37 C.F.R. § 1.56, and without any assertion as to materiality or prior art effect, the documents listed on the attached Form PTO-1449 are hereby cited.

The documents on the attached List are cited in the specification, on pages 2 and 17, and their relevance is addressed therein. Partial translations are also being provided (see the accompanying pages titled "Attached Sheet").

Also attached for the Examiner's information is an English translation of the International Preliminary Examination Report from the parent PCT application.

Respectfully submitted,

By:   
Mitchell W. Shapiro  
Reg. No. 31,568

MWS:pdh

Miles & Stockbridge P.C.  
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May 14, 2001

FORM PTO-1449

Atty. Docket No.

Appln. No.

## LIST OF DOCUMENTS CITED BY APPLICANT

XA-9387

09/714,183

Applicant

Hitoshi TAKEUCHI

Filing Date

November 17, 2000

Group

2877

## U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

## FOREIGN PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Country	Class	Sub-Class	Translation
	AL	59-226317	12/19/84	Japan			Partial
	AM						
	AN						
	AO						
	AP						
	AQ						

## OTHER (including author, title, date, pertinent pages, etc.)

	AR	Parity, vol. 05, No. 10, 1990-10, pp. 37-39 (with partial translation)
	AS	

Examiner

Date Considered

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.